



六、教學進度(Syllabi)	2009/11/10	Pwell formation	許健
	2009/11/17	Oxidation furnace operations	許健
	2009/11/24	Ion implantor	許健
	2009/12/1	Ion implantation setup	許健
	2009/12/8	Implantation monitor	許健
	2009/12/15	PECVD process and monitor	許健
	2009/12/22	CVD process monitor	許健
	2009/12/29	glass reflow and montior	許健
	2010/1/5	Metalization process and monitor	許健
	2010/1/12	Copper metallization process	許健

七、評量方式(Evaluation) test

八、講義位址(<http://>)

九、教育目標

重新查詢